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U.S. PATENT & TRADEMARK OFFICE

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/905,320  
Filing Date ..... July 13, 2001  
Inventor ..... Cem Basceri  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 1762  
Examiner ..... Eric B. Fuller  
Attorney's Docket No. .... MI22-1657  
Title: Chemical Vapor Deposition Methods of Forming Barium Strontium  
Titanate Comprising Dielectric Layers, including such Layers having a Varied  
Concentration of Barium and Strontium within the Layer.

**RULE 312 RESPONSE**

To: Mail Stop Issue Fee  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**VIA EXPRESS MAIL**

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This is responsive to the Notice of Allowance dated November 17,  
2003.

Claims 1-8, 17-22 and 52-66 are in the application. However, the  
Notice of Allowability excludes indication of allowance of claim 66. This is  
believed to be an oversight.